

Supporting Information

Dual-Functional Carbon-Doped Polysilicon Films for Passivating Contact Solar Cells: Regulating Physical Contacts while Promoting Photoelectrical Properties

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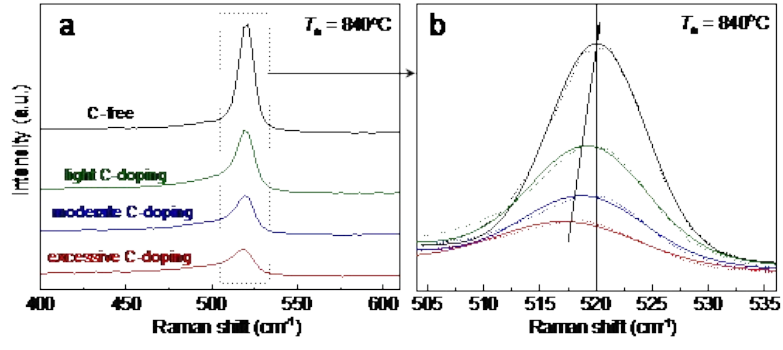


Figure S1. Raman spectra under the different Raman shift ranges at $T_a = 840^\circ\text{C}$.

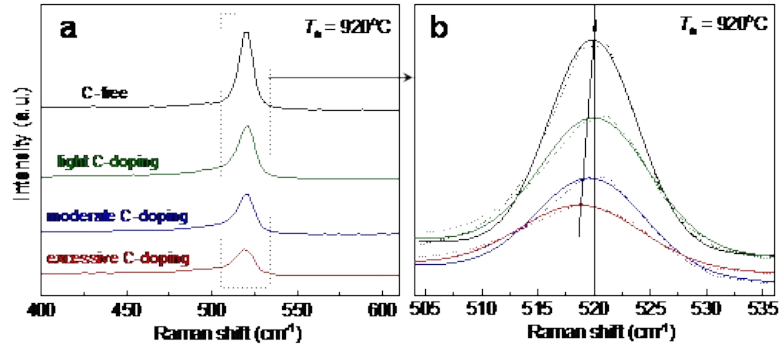


Figure S2. Raman spectra under the different Raman shift ranges at $T_a = 920^\circ\text{C}$.

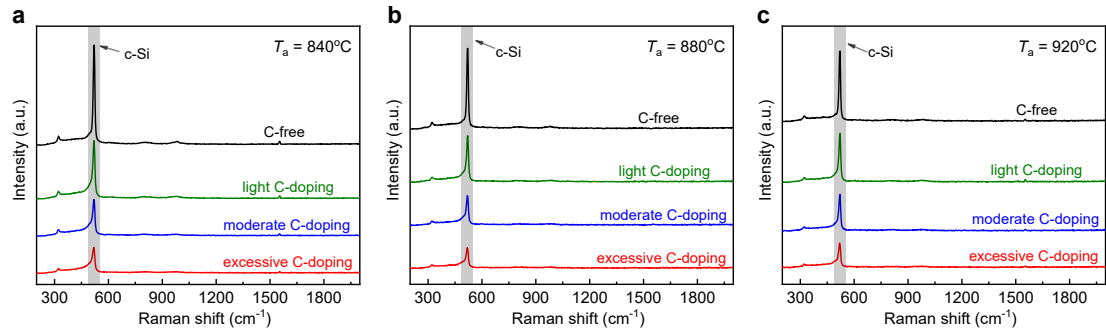


Figure S3. Full Raman spectra for the four related samples at $T_a =$ (a) 840°C, (b) 880°C and (c) 920°C.

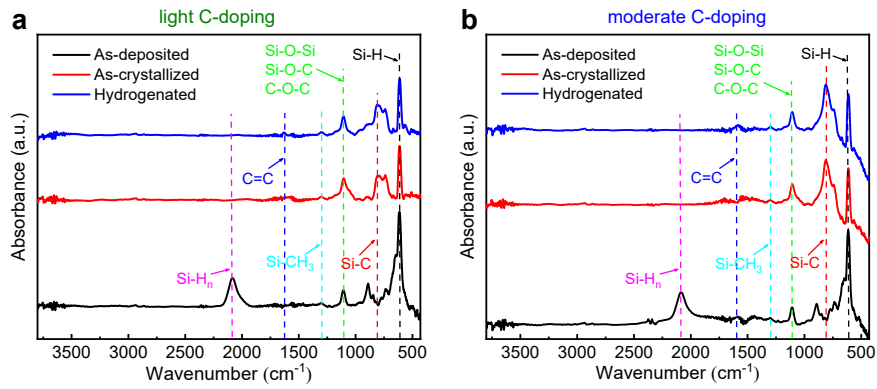


Figure S4. FTIR spectra for the (a) lightly and (b) moderately C-doped samples.

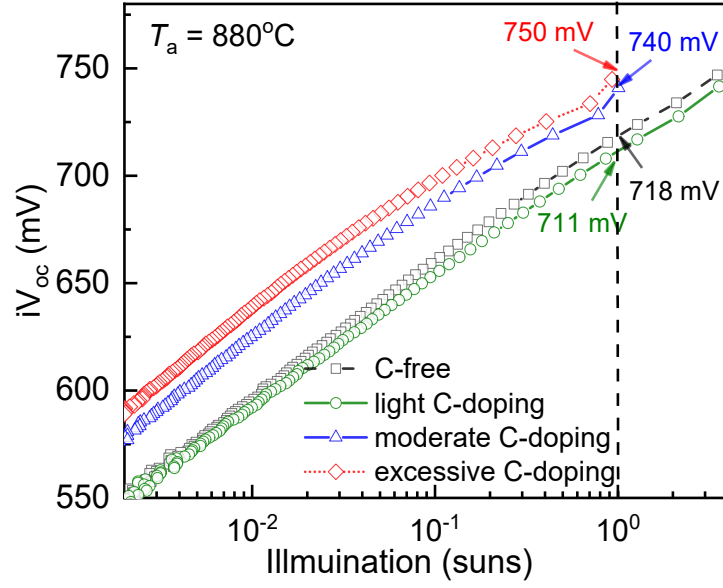


Figure S5. Suns- iV_{oc} for the four related samples at $T_a = 880^\circ\text{C}$.

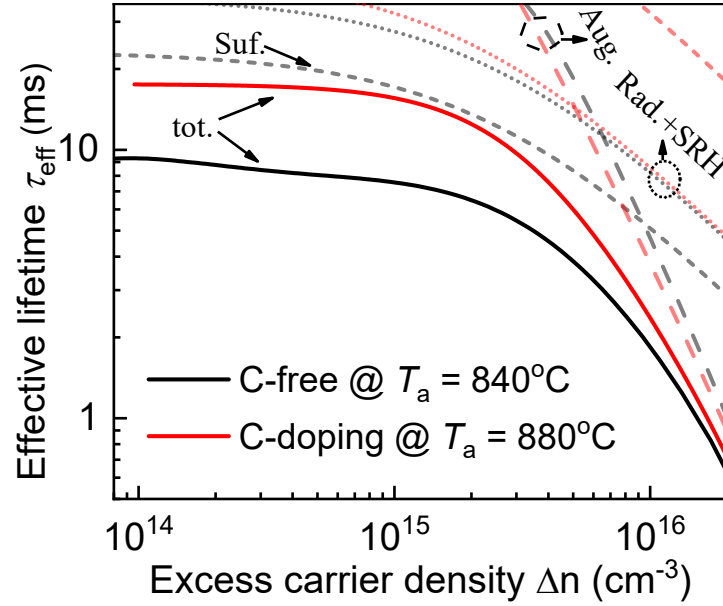


Figure S6. Fitted τ_{eff} as a function of Δn .

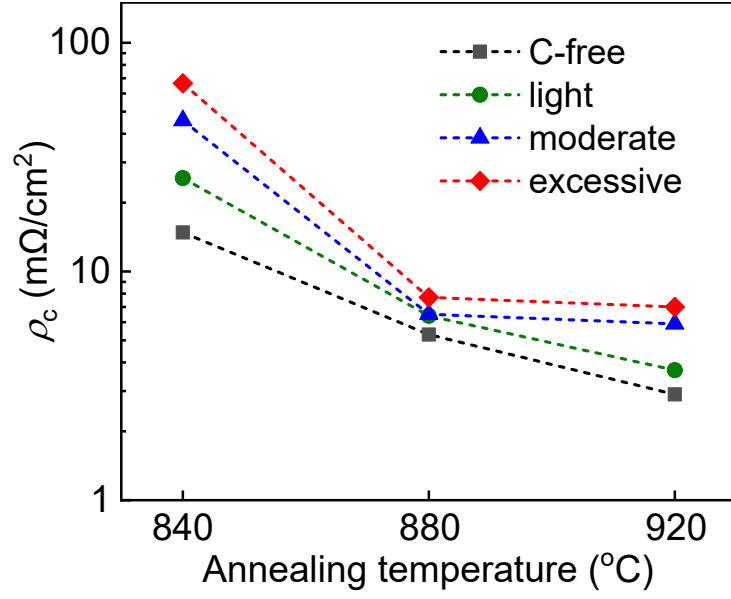


Figure S7. ρ_c as a function of T_a for the C-free and lightly, moderately and excessively C-doped samples.

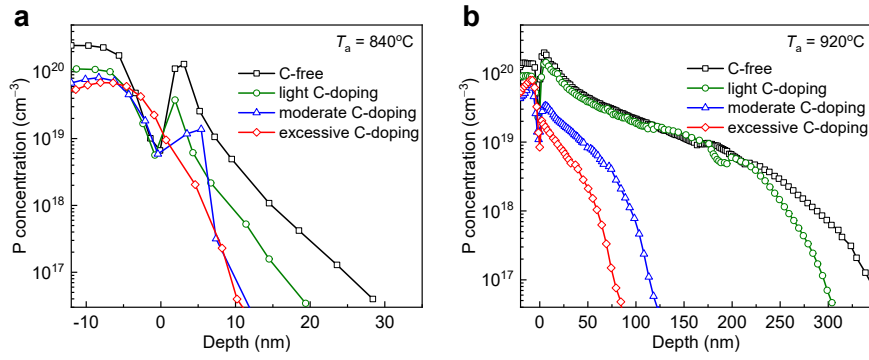


Figure S8. Profiles of active P concentration measured by ECV for the four related samples at T_a = (a) 840°C and (b) 920°C.

Measurement Report

Spectral Response Characteristics

Current-Voltage Characteristics

Report prepared for

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Date: 12 February 2020

Reference: Quotation Number 2019-148

Document ID: SERIS-2019-CHAR-00000114-254-01

Supplementary The reported data are also sent in digital, tabulated format.
Files:

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Measurement Results

3.4. Differential Spectral Response Measurement

The plot of the test solar cell spectral response is shown below.

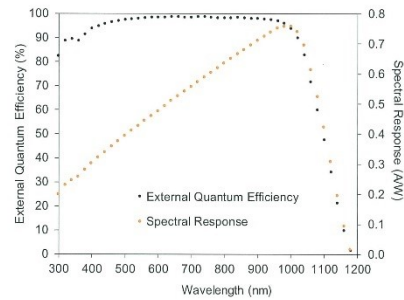


Figure 1. Spectral response of test solar cell D-3

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3.5. One-Sun Current-Voltage (I-V) Characteristics Measurement

The I-V parameters of the test solar cell are shown below.

Table 4. Main I-V parameters for the test solar cell

Sample ID	Open-circuit voltage V_{oc} (mV)	Short-circuit current I_{sc} (A)	Fill factor FF (%)	Area (cm ²)	Efficiency η (%)
D-3	691.5	0.1661	82.83	3.99	23.82

Table 5. Other I-V parameters for the test solar cell

Sample ID	Voltage at max power V_{mp} (mV)	Current at max power I_{mp} (A)	Maximum power P_{max} (W)	Short-circuit current density J_{sc} (mA/cm ²)	Mismatch correction factor
D-3	600.0	0.1586	0.0951	41.6	0.9966

The plot of the test solar cell I-V characteristics is shown below.

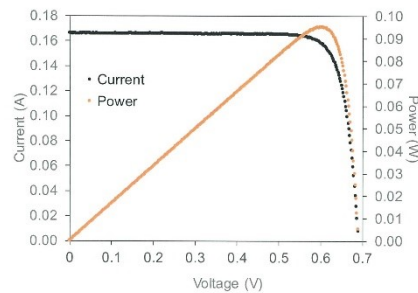


Figure 2. I-V characteristics of test solar cell D-3

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Figure S9. Device certified report by SERIS.

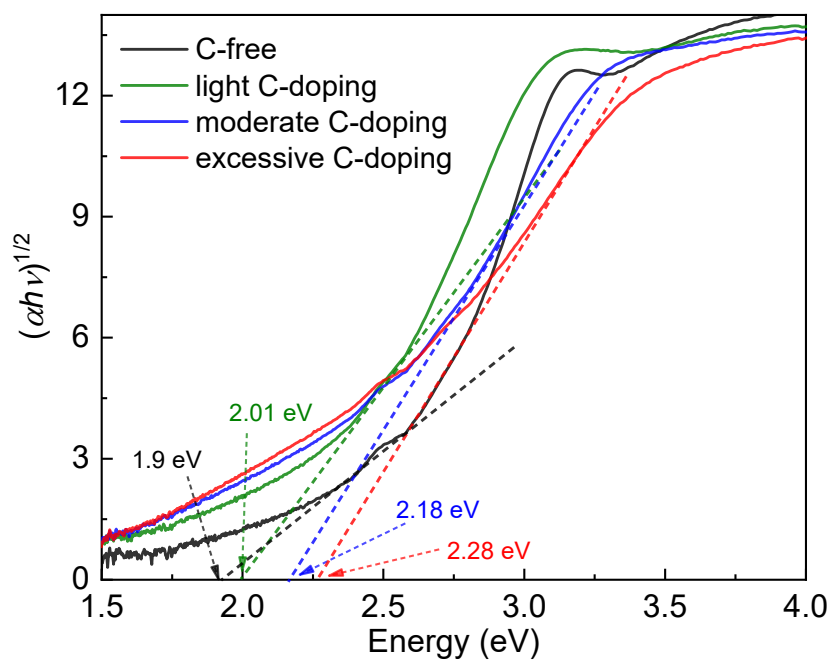


Figure S10. Plots of $(\alpha h\nu)^{1/2}$ vs energy for the four related samples.

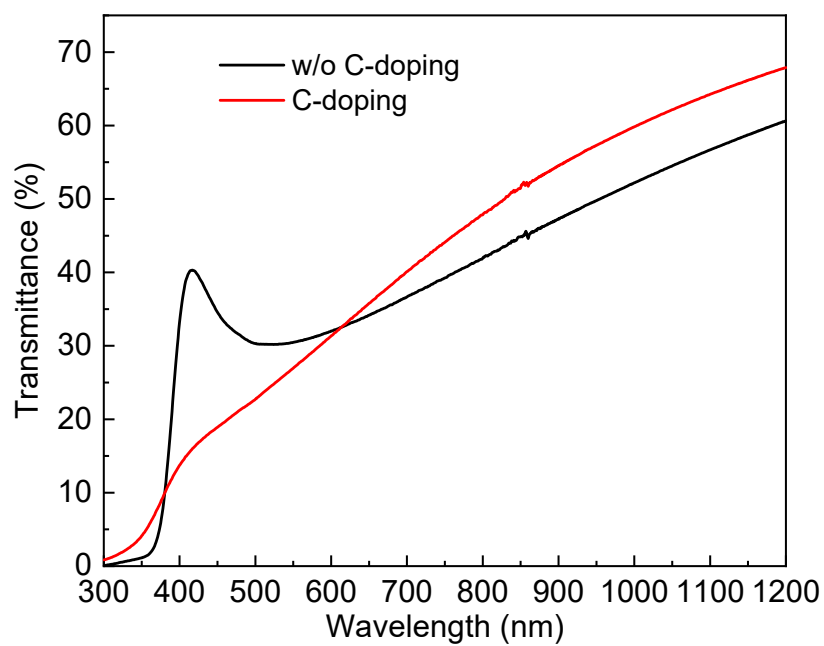


Figure S11. Transmission spectra of the two related cases.

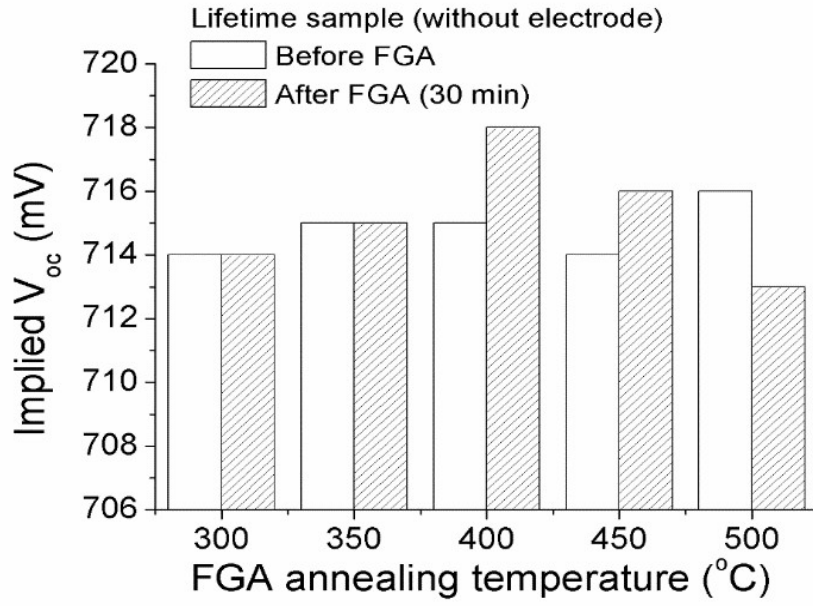


Figure S12. iV_{oc} as a function of the FGA annealing temperatures.

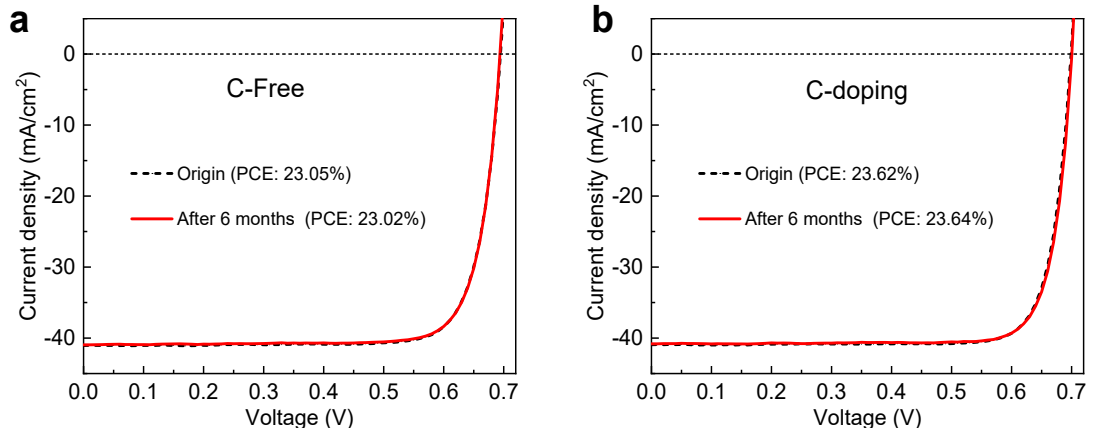


Figure S13. Light J - V curves for the (a) C-free and (b) C-doped samples after 6 months, where the original results are also presented as a reference.

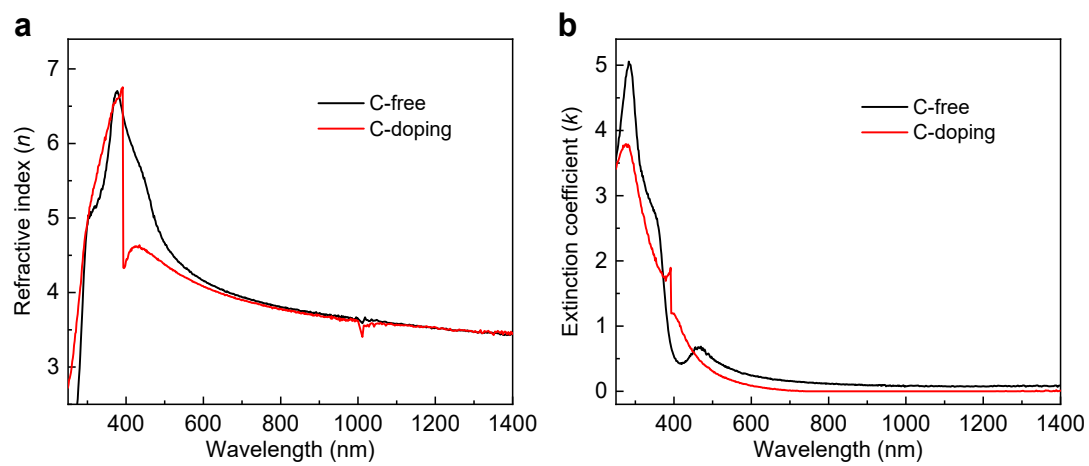


Figure S14. Refractive index of n and k as a function of wavelength.

Table S1. Summary of the previous related works using C doping and other strategies to suppress the blistering.

	Institution	Methods	Performance	Ref.
C-doping	EPFL	A fast thermal annealing nc-SiC _x (P):H	inhibit firing-induced layer delamination and hydrogen effusion; V_{oc} : 698 mV, 21.9% efficiency	1
	IEK5	hot-wire chemical vapour deposition nc-SiC:H(<i>n</i>)	high optical transparency good passivation a certified efficiency of 23.99%	2
	EPFL	PECVD SiC _x (<i>p</i>)	blistering-free; iV_{oc} : 718 mV <i>p</i> - type wafer; 21.9% efficiency	3
	CSEM	PECVD SiC _x (<i>n</i>) & SiC _x (<i>p</i>)	high surface passivation and optical transparency iV_{oc} : 746 mV	4
	TUT	PECVD poly-SiC _x	high passivation quality, high optical transparency at short wavelength, 20.17% efficiency	5
	IEK5	hot-wire chemical vapour deposition μ c-SiC:H(<i>n</i>)	high optical transparency, $J_{sc} >$ 42 mA/cm ² , iV_{oc} of 742 mV	6
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	CNITECH	PECVD C-doped <i>n</i> -type poly-Si	blistering-free; a high iV_{oc} exceeding 750 mV a high efficiency of 24.27% (a certified efficiency of 23.82%)	This work
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Other strategies to suppress blistering	UGA	place the samples in the furnace at low temperature; increase the gas flow ratio $R = H_2/SiH_4$	iV_{oc} : 734 mV	7
	Georgia Tech	Optimize precursor SiH ₄ /PH ₃ flow rate, H ₂ volume ratio and deposition power	iV_{oc} : 730 mV; J_0 : 4.3 fA/cm ² ; 21.2% efficiency on 239 cm ² commercial wafers	8
	CEA-Liten	Optimize the poly-Si thickness, deposition temperature and gas flow ratio	iV_{oc} : 714 mV for poly-Si(<i>p</i> ⁺)	9
		Reduce the substrate heater	iV_{oc} : 733 mV, ρ_c : 90 mΩ·cm ² , an	

-----	IEK5	temperature	ultrafast deposition rate of 150 nm/min	10
	Korea Institute of Energy Research	Investigate the annealing temperature and duration, surface roughness, and deposition temperature	Approaching 700 mV iV_{oc}	11

Table S2. Crystallization fractions and residual stresses of poly-Si films under the different

annealing temperatures.

Samples		C-free	light C-doping	moderate C-doping	excessive C-doping
840°C	crystallization fraction (%)	81.1	71.5	65.8	63.1
	residual stress (MPa)	-174.0	-290.8	-477.2	-1129.8
880°C	crystallization fraction (%)	82.5	73.1	67.4	64.2
	residual stress (MPa)	-29.4	-59.4	-437.2	-665.0
920°C	crystallization fraction (%)	84.8	74.4	70.1	66.7
	residual stress (MPa)	-44.4	-56.5	-133.7	-517.3

Table S3. The iV_{oc} , $J_{0,s}$ and τ_{eff} of double symmetrical poly-Si/SiO_x/c-Si structures under the different annealing temperatures.

Properties	T_a	C-free	light C-doping	moderate C-doping	excessive C-doping
iV_{oc} (mV)	840°C	739	744	745	743
	860°C	720	734	742	744
	880°C	708	711	740	750
	900°C	680	704	727	735
	920°C	668	672	706	719
$J_{0,s}$ (fA/cm ²)	840°C	2.2	1.6	2.2	2.3
	860°C	5.5	4.3	3.0	2.2
	880°C	24.7	14.4	2.9	1.6
	900°C	40	29.9	6.6	3.5
	920°C	72.0	62.0	17.6	9.1
τ_{eff} (ms) @ 1×10^{15} cm ⁻³	840°C	7.51	13.39	12.05	11.58
	880°C	3.2	2.98	9.95	15.36
	920°C	0.54	0.59	2.28	4.33

Table S4. Contact resistivity of poly-Si/SiO_x/c-Si junctions based on CS method under the different annealing temperatures (unit: mΩ·cm²).

Samples	C-free	light C-doping	moderate C-doping	excessive C-doping
840°C	14.8	25.6	45.7	66.5
880°C	5.3	6.4	6.5	7.7
920°C	2.9	3.7	5.9	7.0

Table S5. Sheet resistivity of poly-Si films with a thickness of 40 nm under the different annealing temperatures (unit: Ω/sq).

Samples	C-free	light C-doping	moderate C-doping	excessive C-doping
840°C	108.1	118.0	125.5	161.2
880°C	99.4	112.3	116.7	122.6
920°C	83.2	99.3	109.2	111.1

Table S6. Mobility of poly-Si films under the different annealing temperatures (unit: cm²/V/s).

Samples	C-free	light C-doping	moderate C-doping	excessive C-doping
840°C	32.7	7.63	3.57	3.26
880°C	27.8	8.07	4.82	4.03
920°C	27.6	9.07	6.23	5.43

Table S7. Parameters used for the device simulation.

Parameters	Values
Bulk properties:	
Wafer thickness, W (μm)	170
Wafer resistivity, ρ ($\Omega\cdot\text{cm}$)	1
Background bulk Lifetime, τ_{bulk} (ms)	50
Auger recombination	Richter model
Radiative recombination	Nguyen model
Mobility	Klaassen model
Bandgap narrowing	Schenk model
Front metal grid:	
Space between fingers (μm)	600
Finger width (μm)	10
Front of P^+ emitter:	
Sheet resistance, R_{sheet} (Ω/sq)	105
$J_{0e, \text{met contact}}$ (fA/cm^2)	80
$J_{0e, \text{pass}}$ (fA/cm^2)	100
Contact resistivity ρ_c ($\text{m}\Omega\cdot\text{cm}^2$)	0.1
Junction depth (nm)	850
Rear poly-Si:	
J_0 (fA/cm^2)	Experiment
ρ_c ($\text{m}\Omega\cdot\text{cm}^2$)	Experiment
Parallel resistance R_p ($\text{k}\Omega\cdot\text{cm}^2$)	20
Series resistance R_s ($\Omega\cdot\text{cm}^2$)	0.1
Optical model:	
Passivation & Reflectance Layer (nm)	Experiment
Shading width of fingers	100%

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